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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Confirmation No.: 7420

Takaei SASAKI et al. Group Art Unit: 1746

Serial No.: 10/706,944 Examiner: Michail Kornakov

Filed: November 14, 2003 Attorney Docket No.: 101136-00103

For: **METHOD AND APPARATUS FOR DRY-ETCHING HALF-TONE PHASE-SHIFT FILMS, HALF-TONE PHASE-SHIFT PHOTOMASKS AND METHOD FOR THE PREPARATION THEREOF, AND SEMICONDUCTOR CIRCUITS AND METHOD FOR THE FABRICATION THEREOF**

AMENDMENT UNDER 37 CFR §1.111

Mail Stop Amendment

Director for the U.S. PTO

P.O. Box 1450

Alexandria, VA 22313-1450

Date: June 7, 2004

Sir:

In reply to the outstanding Office Action dated April 22, 2004, please amend the application as shown on the following pages: